

# Optical components for Earth observation instruments

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## Components for space spectrometers with exceptional accuracy

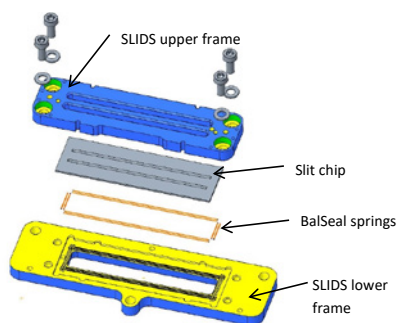
We design, manufacture, and integrate highly precise slit assemblies for spectrometer applications with mechanical accuracy of the slits down to the sub-micron range in absolute width and length, and a slit planarity less than 5  $\mu\text{m}$ .

# SLITA – slit assembly for the FLEX mission

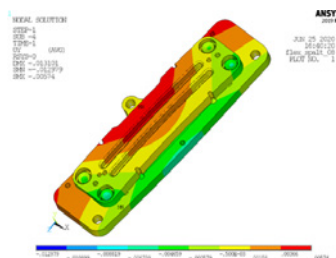
The “Fluorescence Imaging Spectrometer” (FLORIS) will be the heart of ESA’s “Fluorescence Explorer Mission” (FLEX). For the spectrometer, the IOF developed and manufactured a double-slit assembly with exceptional accuracy as well as two high-precision mirrors in cooperation with OHB. The requirements were at the limits of what is technically feasible. Each slit must be manufactured with an exact width of  $85(\pm 1) \mu\text{m}$  over a length of 44.15 mm. Both slits are mounted highly parallel to each other and have a slit planarity of less than  $10 \mu\text{m}$ . Special requirements also applied to the mirrors, which are intended to guide the light onto the detector inside the spectrometer: These had to have a roughness requirement of 0.3 nm rms (root mean square).

## Design and analysis

- Two mechanical parts – upper and lower frame
- Slit will be clamped and fixed by mechanical springs
- Planarity of mechanical parts defines the slit planarity
- Additional fixation by dot of adhesive to prevent thermal induced position deviations of slit up to end of life
- The maximum of the corresponding out-of-plane deformation of the slits chip amounts to  $5.7 \mu\text{m}$  while a maximum out of plane deformation of  $3.5 \mu\text{m}$  occurs at the slit edges



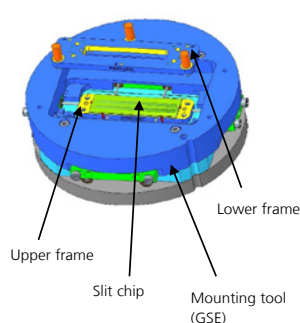
Design of double slit device (SLIDS)



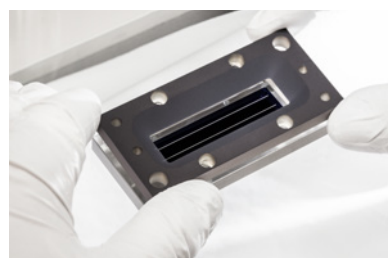
Out-of-plane deformation of the upper and lower frame

## Manufacturing and integration

- Slit structure was fabricated by a lithographic exposure processes in combination with a silicon wet-etching processes
- Special tools have been developed for mounting and positioning of upper and lower frame and slit chip
- The integration and positioning concept use mechanical references of GSE for slit chip alignment
- The final position was measured by contact-less optical coordinate measurement



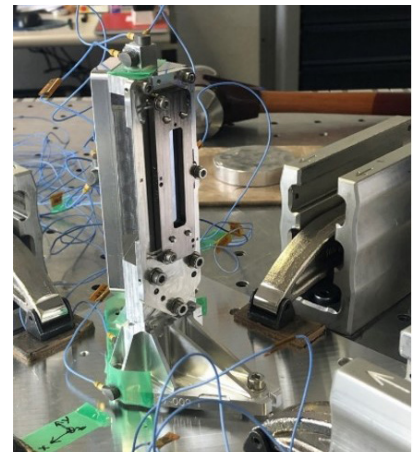
CAD image of assembly tool



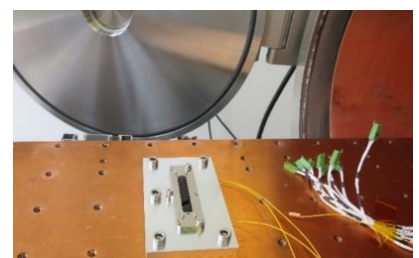
Black coating GSE for slit chip

## Testing

- Thermal-vacuum cycle test with 25 cycles and a temperature range from  $-25^\circ\text{C}$  to  $+65^\circ\text{C}$
- Shock test was performed along x-, y- and z-axis. Per each axis three shocks were applied.
- Vibration tests were performed along x-, y- and z-axis. Per each axis the sine and random vibration loads were applied.



SLIDS during shock test (z-axis)



SLIDS on thermal adapter of thermal vacuum chamber





*Top:*

*Researchers at Fraunhofer IOF check the bidirectional positioning accuracy of slit chip with respect to the mechanical interfaces during the assembly process*

*Cover:*

***SLITA – slit assembly for the “Fluorescence Imaging Spectrometer” (FLORIS)***

*The FLEX Slit Assembly was developed with financial and technical support from the European Space Agency (ESA) in the frame of the Earth Explorer – Fluorescence Explorer (FLEX) mission.*



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info

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